



Atty. Dkt. No. 039262-0154

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Tadahiro OHMI et al.  
Title: PLASMA PROCESSING APPARATUS  
Appl. No.: 10/584,137  
Filing Date: 8/1/06  
Examiner: Keath T. Chen  
Art Unit: 1792  
Confirmation No.: 4094

**AMENDMENT AND REPLY UNDER 37 CFR 1.116**

Mail Stop **BOX AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Final Office Action dated November 5, 2008, concerning the above-referenced patent application.

Applicants have submitted herewith a petition and fee for a three-month extension of time, to make this response timely.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this document.

**Remarks/Arguments** begin on page 5 of this document.

Please amend the application as follows:

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